

Introduction

Molten salt reactors and pyro-processing environments contain alpha particle emitting actinides. By deploying a detector sensitive to alpha particles, the ratio of the actinides may be determined. Devices in the molten salt environment will be subjected to high temperatures, high radiation fluences, and corrosion. Schottky barrier diodes made from wide bandgap semiconductors, such as 4H-SiC, have already been shown to be able to measure alpha spectra at high temperatures, but have been limited to 450 °C. Ultrawide bandgap semiconductor, β -Ga₂O₃ is being investigated for deployment in environments of 550-750 °C.



Thermal Investigations

- performed on a Signatone S-1060RH high temperature hot chuck
- Sensitivity to alpha particles were demonstrated by collecting spectra of 5.486 MeV alpha particles from a 1 µCi button source of ²⁴¹Am. 800.0 — 100 V — 70 V 3000 Temperature dependent measurements were 0.006 — 50 V **Ö** 0.004 **Ŭ** 2000 • Following pthermal cycling of device, a reduction 1000 0.002 in leakage current at room temperature was noticed Current-voltage sweep was performed while being Channel 0.035 held at temperatures at 50 °C intervals 0.030 • Contact failure occurred at 250 °C - Old Wafer 0.025 - New Wafer 0.020 no 0.015 0.010 0.005

Experimental Demonstration of Ga2O3 as a Radiation Sensor and Its High Temperature Resistance

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Goals and Objectives

- To fabricate Schottky barrier diodes from β -Ga₂O₃ as alpha particle detectors.
- Demonstrate sensitivity to alpha particles
- Determine electrical performance and sensitivity dependence on temperatures up to 750 °C.



Epilayer grown by Hydride Vapor Phase Epitaxy

Results

1000

Channel

0.000

Schottky Contact with Guard Ring

Contact Size: 0.785 mm² **Epitaxial Layer Thickness:** 11.0 µm **Dopant Concentration**: 3.7×10^{16} cm⁻³ **Substrate Thickness**: 640 µm



A second wafer has been procured from NCT, Japan. The new wafer has an average doping concentration of 7×10^{15} cm⁻³

An increase in count rate $\sim 14x$ while utilizing the same design

Electrical Characterization

breakdown



layer

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Current-voltage sweeps were performed to determine reverse bias leakage current and device

Capacitance-voltage measurements were also performed to determine built in voltage and to view dopant profile

Conclusions

Preliminary alpha spectra was achieved from a Ga_2O_3 Schottky barrier diode without the use of a passivation

It will be necessary to extend the breakdown voltage to achieve the desired charge collection Thermal experiments have shown the necessity for more robust temperature resistant contacts

Acknowledgments



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